

Atty. Dkt No.
33082M123



JC10 Rec'd PTO 12 APR 2002

PATENT

THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: Masayuki TOMOYASU

Serial No.: 10/049,989

Group Art Unit: Unassigned

Customer No. 00441

Filed: February 20, 2002

Examiner: Unassigned

For : PLASMA PROCESSING SYSTEM AND PLASMA PROCESSING METHOD

SECOND INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
Washington, D.C. 20231

Sir:

RECEIVED
JUN 17 2002
TECHNOLOGY CENTER 1700

Pursuant to the duty of disclosure under 37 C.F.R. 1.56, Applicant is enclosing an Information Disclosure Citation Form (PTO-1449) and a copy of the document cited therein.

It is respectfully requested that the cited document be considered by the Examiner in the above-identified patent application and that the cited document be made officially of record therein. It is further requested that a listing of the same appear on the face of any patent which may issue from this application.

The complete Japanese specification and its English abstract are provided herewith. In addition, the inventor wishes to point out a portion of the disclosure of JP 3-206613 that has been translated into English. The inventor also points out Fig. 1 as related to the present invention.

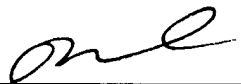
The English translation of the disclosure portion which the inventor wishes to highlight is presented below. This translation portion corresponds to the text within the red-ink rectangle on page (4) (lower page No. 62) of the copy of JP 3-206613 provided herewith.

"An output of an rf current may either be directly connected to an electrode 27 as is generally done, or connected to a cool storage unit 35 as shown in the drawing. In the latter case, since a narrow gap 33 of a heat transfer unit 30 has a large electrostatic capacity, an rf electric power is transferred to the electrode 27 through the narrow gap 33.


A control of a wafer temperature, when etching a wafer by employing an apparatus of an embodiment, is described.”

This Information Disclosure Statement is being filed within three months of the filing date of the present application, and therefore it is believed that no fees are due under 37 C.F.R. Section 1.97(i).

Respectfully submitted,
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April 12, 2002

FORM PTO-1449 INFORMATION DISCLOSURE STATEMENT 	ATTY. DOCKET 33082M123	SERIAL NO. 10/049,989
	APPLICANT: Masayuki TOMOYASU	
	FILING DATE February 20, 2002	GROUP ART UNIT To Be Assigned

U.S. PATENT DOCUMENTS

*Examiner's Initials		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB-CLASS	FILING DATE, IF APPROPRIATE
	AA						
	AB						
	AC						
	AD						
	AE						
	AF						
	AG						

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FOREIGN PATENT DOCUMENTS

*Examiner's Initials		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUB-CLASS	TRANSLATION YES NO	
	AH	3-206613	9/10/1991	JAPAN			Abstract	
	AI							
	AJ							
	AK							
	AL							
	AM							
	AN							
	AO							
	AP							

OTHER INFORMATION (Including Author, Title, Date, Pertinent Pages, Etc.)

	AQ	
	AR	
	AS	
	AT	
EXAMINER:		DATE CONSIDERED:
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.		